

# Size-Dependent Strain Relaxation and Optical Characteristics of InGaN/GaN Nanorod LEDs

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**Abstract**—In this paper, InGaN/GaN nanorod LEDs with various sizes are fabricated using self-assembled Ni nanomasks and inductively coupled plasma-reactive ion etching. Photoluminescence (PL) characteristics exhibit size-dependent, wavelength blue shifts of the emission spectra from the nanorod LEDs. Numerical analyses using a valence force field model and a self-consistent Poisson, Schrödinger, and drift-diffusion solver quantitatively describe the correlation between the wavelength blue shifts and the strain relaxation of multiple quantum wells embedded in nanorods with different averaged sizes. Time-resolved PL studies confirm that the array with a smaller size exhibits a shorter carrier lifetime at low temperature, giving rise to a stronger PL intensity. However, the PL intensity deteriorates at room temperature, compared to that of a larger size, possibly due to an increased number of surface states, which decreases the nonradiative lifetime, and hence reduces the internal quantum efficiency.

**Index Terms**—LEDs, nanotechnology.

## I. INTRODUCTION

III-NITRIDES have become prominent materials for optoelectronic devices and high power electronics [1]–[6]. The bandgaps of III-nitride alloys are continuously tunable from 6.2 to 0.7 eV, which covers the entire UV to near infrared spectrum. The wide direct bandgap property makes III-nitrides particularly promising for UV and blue LEDs. Moreover, it is also possible to convert the UV and blue into green and red light for white light sources with the assistance of phosphors. However, due to the large lattice mismatch  $\sim 10\%$  between InN and GaN for crystal growth along the *c*-axis, the InGaN/GaN multiple quantum wells (MQWs) suffer an epitaxially induced strain, leading to a strong piezoelectric field inside the wells, and worsening the crystalline quality. The resulting quantum-confined Stark effect (QCSE) further limits the internal quantum efficiency of InGaN/GaN MQW LEDs. Recently, the advances in nanofabrication technologies have allowed the fabrication of GaN-based

nanostructures [7]–[11], posing a viable solution to relieving the strain in MQWs using nanostructured LEDs and potentially pushing to longer emission wavelengths with higher compositions of indium. Multiple studies have also been made on optical properties of the GaN-based nanostructures [10], [12]. In our recent work, we have demonstrated a single, free-standing GaN-based nanorod with a diameter of 300 nm using the focused ion beam (FIB) technique [12]. The microphotoluminescence ( $\mu$ -PL) from the embedded GaN/InGaN MQWs reveals an energy blue shift of 68.3 meV contributed by the strain relaxation in MQWs. Still, few reports had yet been made for the size-dependent, strain relaxation effects on the emission characteristics. In this study, InGaN/GaN nanorod LEDs with a height of  $\sim 700$  nm and averaged sizes ranging from 120 to 300 nm are fabricated using self-assembled Ni clusters as the etch masks and inductively coupled plasma-reactive ion etching (ICP-RIE). Both frequency- and time-resolved PL (TRPL) characterizations are performed to analyze the size-dependent emission characteristics. Furthermore, a valence force field (VFF) model is developed to study the strain relaxation properties of InGaN/GaN MQWs embedded in the nanorod structures. The strain distribution and strain-induced polarization effect inside the MQWs is added to our self-consistent Poisson, drift-diffusion, and Schrödinger solver to analyze the emission characteristics in details. The emission spectra from nanorod LEDs of various sizes and under different carrier injection conditions are calculated, where reasonable agreements with the experimental results are obtained.

## II. FABRICATION

As illustrated in Fig. 1, the GaN nanorod LEDs of different averaged sizes were fabricated by a relatively simple method, using self-assembled Ni nanoclusters as the etch masks and ICP-RIE process. The samples were grown by metal-organic chemical vapor deposition (MOCVD) with a rotating-disk reactor on a *c*-plane sapphire (0 0 0 1) substrate at a growth pressure of 200 mbar. The epitaxial structure consisted of a 30-nm-thick GaN nucleation layer, a 2- $\mu$ m-thick unintentionally doped GaN buffer layer, a 2- $\mu$ m-thick Si-doped n-GaN layer, an unintentionally doped InGaN/GaN MQW active region, and a 0.2- $\mu$ m-thick Mg-doped p-GaN. The MQW active region consists of ten pairs of 3- and 7-nm-thick InGaN wells and GaN barriers.

Fig. 1 illustrates the fabrication process of the nanorod LEDs with embedded InGaN/GaN MQWs. Based on our previous experimental results, a thin metal film can be self-assembled into nanoscaled islands after rapid temperature annealing (RTA), and the metal islands can result in better distribution

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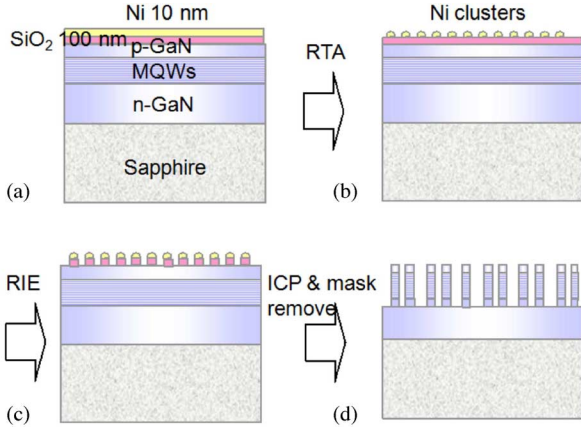


Fig. 1. Fabrication processes of nanorod LED arrays.

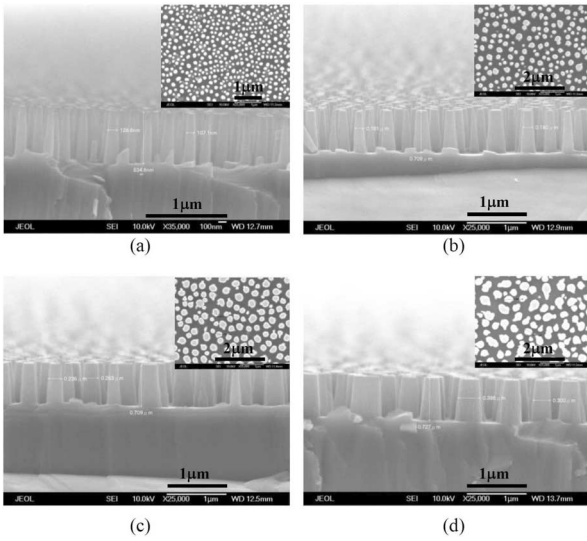


Fig. 2. Cross-sectional, SEMs of the fabricated GaN nanorod LEDs. The averaged diameters from (a) to (d) are 120, 180, 220, and 300 nm, respectively. The corresponding insets show the top view images of Ni-nanoscaled islands.

uniformity with a dielectric film deposited underneath the metal layer. Therefore, a 100-nm-thick SiO<sub>2</sub> layer was first deposited on the epi-surface of LEDs by plasma-enhanced chemical vapor deposition (PECVD). Then, an Ni film with various thicknesses of 5, 10, 15, and 20 nm was evaporated on SiO<sub>2</sub> layer using an electron beam evaporating system [Fig. 1(a)], followed by the RTA process with an N<sub>2</sub> flow rate of 10 SCCM at 850 for 90 s to form Ni nanoclusters, serving as the etching masks [Fig. 1(b)]. Since the RTA environments were identical for all the four samples, the different Ni thicknesses result in different averaged diameters and densities of the nanoclusters. Hence, the nanorod LEDs with various sizes could be fabricated. All samples with Ni nanomasks were subsequently performed using RIE and ICP to transfer the nanoscaled pattern into the SiO<sub>2</sub> layer [Fig. 1(c)] and GaN under the same etching condition. Finally, remove both the Ni metal masks and SiO<sub>2</sub> in heated nitric acid and buffered oxide etchant (BOE) [Fig. 1(d)]. Details of the nanomasks formation process were described in [13].

Fig. 2(a)–(d) shows the cross-sectional, SEMs of the fabricated GaN nanorod LEDs. The corresponding insets show the

top view images of Ni-nanoscaled islands fabricated with metal thicknesses of 5, 10, 15, and 20 nm. From these images, all fabricated nanorod LEDs have a nearly identical height of  $\sim 700$  nm. The averaged diameters were  $\sim 120 \pm 20$ ,  $180 \pm 20$ ,  $220 \pm 20$ , and  $300 \pm 30$  nm with densities decreasing from  $3 \times 10^9$  to  $5 \times 10^8$  cm<sup>-2</sup>.

### III. THEORETICAL MODEL

In order to analyze the correlation between the strain relation and emission characteristics, the VFF model [12], [14], [15] is developed to calculate the strain distribution of the nanorod LEDs. The VFF model is a microscopic model, where the interactions between each atom and its nearby atoms are considered. The total elastic energy is expressed as a function of atomic positions  $\vec{R}_i$  using the summation of bond stretching ( $V_2$ ) and bond bending ( $V_3$ ) terms

$$\begin{aligned}
 E_{AE} &= \sum_{ij} V_2(\vec{R}_i - \vec{R}_j) + \sum_{ijk} V_3(\hat{\theta}_{ijk}) \\
 &= \frac{1}{2} \sum_i \sum_j^{nn} \frac{3\alpha_{ijk}}{8(d_{ij}^0)^2} [(\vec{R}_i - \vec{R}_j)^2 - (d_{ij}^0)^2]^2 \\
 &\quad + \frac{1}{2} \sum_i \sum_{j,k>j}^{nn} \frac{3\beta_{ijk}}{8d_{ij}^0 d_{ij}^0} [(\vec{R}_j - \vec{R}_i) \cdot (\vec{R}_k - \vec{R}_i) \\
 &\quad - \cos \theta_0 d_{ij}^0 d_{ij}^0]^2
 \end{aligned} \tag{1}$$

where  $d_{ij}^0$  denotes the unstrained bond length between atoms  $i$  and  $j$ , and  $\theta_0$  is the unstrained bond angle, and  $\cos \theta_0 = -1/3$ . The bond stretching  $\alpha$  and bond bending  $\beta$  force constants are listed in Mattila and Zunger [14]. The strain energy of each atom is minimized by an iterative method to find the most stable configuration. Once the system reaches the lowest energy, the strain distribution inside the structure can be obtained.

After obtained the strain distribution of the QW inside the nanorod structure, we can obtain the piezoelectric polarization induced by the strain, expressed as

$$P_{ez} = e_{31}(\epsilon_{xx} + \epsilon_{yy}) + e_{33}\epsilon_{zz} \tag{2}$$

where  $e_{31}$  and  $e_{33}$  are the piezoelectric coefficients and can be found in Ambacher *et al.* [16]. After obtaining the piezoelectric polarization, the fixed polar charge density can be obtained from the difference of the piezoelectric and spontaneous polarization field.

Since  $P_{ez}$  is a distribution function of  $x$ ,  $y$ , and  $z$ , we can calculate the piezoelectric polarization-induced charge densities of each unit cell by

$$\rho_{pz}(x, y, z) = \frac{P_{ez}(x, y, z + dz) - P_{ez}(x, y, z)}{dz}. \tag{3}$$

The calculated distribution of the polar charges inside the MQW is then used in the self-consistent Poisson, Schrödinger, and drift-diffusion solver developed in our lab [17] to calculate the band diagram, the emission spectrum, and the emission intensity under different charge conditions. Since all of our simulation results are from the PL measurement, in order to accurately model the band structure after light absorption from the laser

light source, we also apply a generation term in the continuity equation (drift-diffusion) to model the carriers generated from light absorption, expressed as

$$\nabla \vec{J}_{n,p} = q(G - R) \quad (4)$$

where  $R$  is the carrier recombination rate from either radiative channel or nonradiative channel;  $G$  is the carrier generation term and depends on the excitation strength and the material absorption coefficient. The emission rate of MQWs inside the nanorod can be expressed as [18]

$$R_{spont} = \int d(\hbar\omega) \frac{e^2 n_r \hbar\omega}{m_0^2 \varepsilon_0 c^3 \hbar^2} \sum_{i,j} \int \frac{2}{(2\pi)^2} dk |\hat{a} \cdot \mathbf{p}_{i,j}|^2 \times \frac{1}{\sqrt{2\pi}\sigma} \exp\left(\frac{-(E_{i,j} - \hbar\omega)^2}{2\sigma^2}\right) f^e f^h \quad (5)$$

where  $E_{i,j}$  is the averaged energy separation between the electron state  $i$  and hole state  $j$ ,  $n_r$  is the refractive index, and  $\sigma$  is the inhomogeneous broadening factor.  $f^e(\mathbf{k})$  and  $f^h(\mathbf{k})$  are the Fermi-Dirac distribution of electrons and holes, respectively.  $|\hat{a} \cdot \mathbf{p}_{i,j}|^2$  is the momentum matrix element between the electron state,  $i$ , and the hole state,  $j$ . With the electronic band structures and the energy states obtained from the self-consistent solver, we can apply (5) to study the relative intensity of the emission spectrum, wavelength shift, and the screen and band-filling effects at various carrier injection conditions.

#### IV. RESULTS AND DISCUSSION

Fig. 3(a) and (b) shows the measured PL from a regular LED and nanorod LEDs with various average diameters at low temperature 20K and room temperature, respectively. The pumping powers for all measurements are 15 mW at a laser spot size of 200  $\mu\text{m}$ . As shown in Fig. 3(a), as the averaged rod diameter becomes smaller, the emission peak shows a clear blue shift. The PL intensity is strongest for LEDs with the smallest averaged diameter, 120 nm. The intensity decreases as the diameter becomes larger. However, the PL characteristics at room temperature are slightly different from those at the low temperature 20 K. First, the emission peak still has a clear blue shift as the diameter becomes smaller. Second, the PL intensity is strongest for LEDs with an averaged diameter of 220 nm. PL intensities are deteriorated at room temperature for nanorod LEDs of 120 and 180 nm. The PL intensity of the regular LED is much weaker than nanorod LEDs due to a stronger QCSE and lower light extraction efficiency. Fig. 4 shows the peak energy shift versus the rod diameters. The PL peak position of the regular LED is also plotted as the reference point. We can find that the fitted slopes at room temperature and 20 K are around 17.047 and 16.323 eV·nm, respectively.

The changes in PL intensity could be due to the absorption of excitation, the emission volume, light extraction efficiency, and defect densities of the nanorod LEDs. Therefore, it is hard to quantitatively analyze the size-dependent characteristics of the PL intensity and we will discuss qualitatively later. On the other hand, the blue shift of the spectrum is large ( $>100$  meV) and cannot be simply explained by the band-filling effect or the

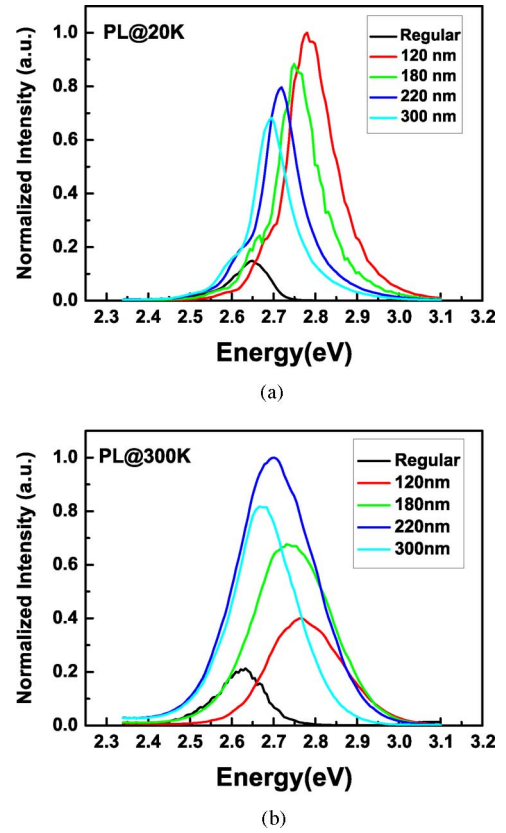


Fig. 3. PL spectra of a regular LED and nanorod LED arrays with different sizes at (a) 20 K and (b) room temperature.

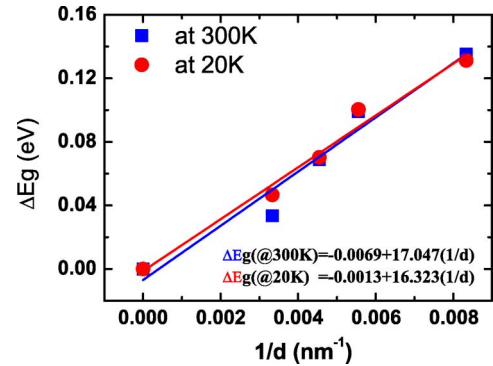


Fig. 4. Measured peak shift and fitted curve versus nanorod diameters at room temperature and at 20 K.

carrier screening of QCSE. In particular, the power density of PL is not strong enough to induce a very high carrier density in the MQWs. The other possibility is the strain relaxation of the QW [12]. For InGaN/GaN, QW structures grown along  $c$ -axis, there exists a strong strain-induced piezoelectric polarization field inside the device. This will contribute to the band bending and red shift of spectrum, known as the QCSE. For the QW structure at the edge of nanorod surface, the lateral confinement of the QW is weak such that the relaxation of the InGaN QW layer is possible. The relaxed strain reduces the piezoelectric field inside the QW so that the spectrum shows a blue shift of the

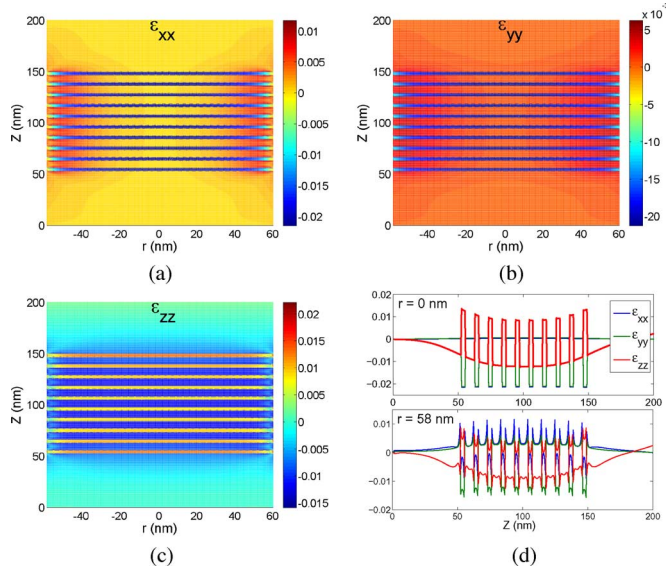


Fig. 5. Calculated strain distributions of  $\text{In}_{0.2}\text{Ga}_{0.8}\text{N}/\text{GaN}$  MQWs embedded in a free-standing, cylindrical-shaped nanorod with a height of  $Z = 200$  nm and a width of  $d = 120$  nm for (a) in-plane strain tensor  $\epsilon_{xx}$  and (b) in-plane strain tensor  $\epsilon_{yy}$ , (c) vertical strain tensor  $\epsilon_{zz}$ , and (d) 2-D plots of strain tensors at the center and at the edge of the nanorod.

emission wavelength. This blue shift should be observed for low-power, high-power, low-temperature, and room-temperature PL measurements.

In order to confirm the observed wavelength blue shift, we first apply the VFF model described in (1) in the previous section. Once the atoms' positions are known, calculating the strain tensor distribution is straightforward. To maintain the symmetry in a wurtzite structure, free-standing, cylindrical-shaped GaN nanorods consisting of ten-pair  $\text{In}_{0.2}\text{Ga}_{0.8}\text{N}$  MQWs are defined with various diameters ranging from 120 to 300 nm. The nanorod has a fixed boundary condition at the bottom and free boundary conditions on other sides. Fig. 5 shows the calculated strain distribution for the nanorod with a diameter equal to 120 nm. Fig. 5(a)–(c) shows the strain tensor  $\epsilon_{xx}$ ,  $\epsilon_{yy}$ , and  $\epsilon_{zz}$  of the cross section of  $x - z$  plane at the center of  $y$ -axis, respectively. Fig. 5(d) shows the line plot at  $r = 58$  nm and  $r = 0$  nm (center) of strain tensor. Both strain tensors show considerable relaxations on the outer shell of the nanorod, and as-grown-like strain distributions in the center of the nanorod. As shown in Fig. 5(a), the strain relaxation of  $\epsilon_{xx}$  occurs at a distance of 20 nm from the edge of the nanorod. At  $r = 58$  nm, where the change of strain from the nanorod center is most significant, there exist substantial strain variations on the QW/barrier interfaces and a slight tensile strain of  $\epsilon_{xx}$  in the barriers. There is also a slight strain relaxation of  $\epsilon_{yy}$  due to the circular shape of the rod. We also observe a vertical distribution of  $\epsilon_{zz}$  in the  $Z$ -direction, mainly arising from the stacking of MQWs.

Fig. 6(a)–(d) shows the strain tensors  $\epsilon_{xx}$  for nanorod diameters equal to 120, 180, 220, and 300 nm, respectively. As shown in Fig. 6, the major strain relaxation region is limited to 20 nm from the edge, regardless of the rod diameters. Therefore, the ratio of strain-relaxed MQW region to the strained region size

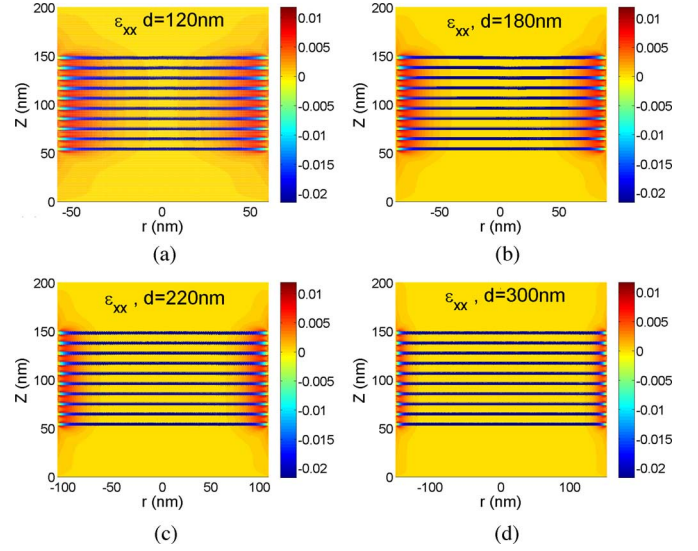


Fig. 6. Calculated strain  $\epsilon_{xx}$  for nanorod LEDs with various averaged diameters. (a) 120 nm. (b) 180 nm. (c) 220 nm. (d) 300 nm.

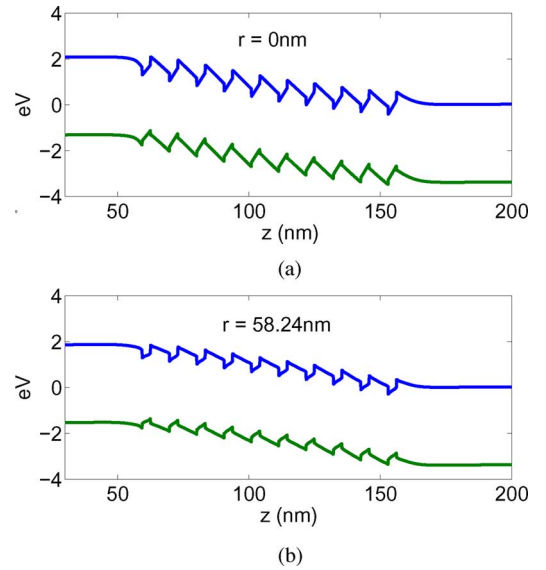


Fig. 7. Calculated conduction and valence band profiles of the MQWs embedded in a nanorod with a diameter of 120 nm at (a) center ( $r = 0$  nm) and (b) edge ( $r = 58.24$  nm) of the nanorod.

becomes larger as the diameter decreases. With the calculated strain information, it is possible to calculate the emission spectra of nanorod LEDs with different sizes. Both in-plane and vertical strain tensors contribute to the polarization field and can be calculated by (2). Based on the calculated strain, as shown in Fig. 5, and the induced polarization charge calculated by (3). The calculated results are subsequently inserted into the self-consistent Poisson, Schrödinger, and drift-diffusion solver to calculate the band structure of the MQWs. The parameters needed for the band structure calculation can be found in Ambacher *et al.* [16].

Fig. 7 shows the calculated band structures of the ten-pair MQW structure for different strain conditions: (a) at the center and (b) at the edge of the nanorod with a diameter of 120 nm.



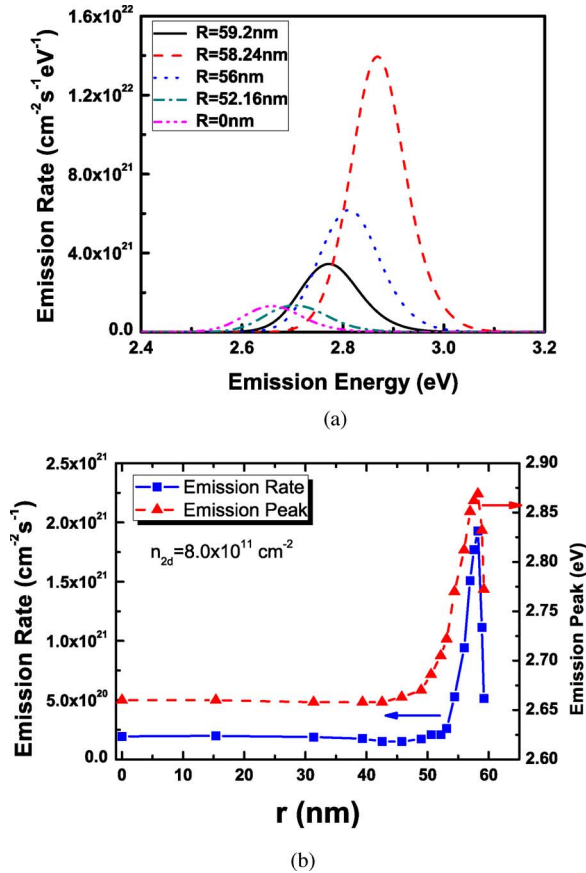


Fig. 8. (a) Calculated spontaneous emission rates as a function of emission energy at different positions of the nanorod with a diameter of 120 nm under the injected electron density at  $8 \times 10^{11} \text{ cm}^{-2}$ . (b) Calculated spectrum peak shift and emission rates from the center to the edge of the nanorod.

The polarization charge density induced by strain is taken into account as a function of the depth and the spontaneous polarization. As shown in Fig. 7, the band bending at the center of the nanorod is the strongest while the band bending at the edge is the weakest at  $r = 58 \text{ nm}$ , where the strain relaxation reaches the maximum. In order to compare the PL intensity and compare the energy shift of the emission peak at different regions, we use the eigenfunctions and eigen levels obtained from (5) to calculate the emission intensity and the energy shift. The calculated results are shown in Fig. 8.

Fig. 8(a) shows the calculated emission spectra of the MQW structure at different regions of the nanorod structure with a diameter of 120 nm and under an injected electron density of  $8 \times 10^{11} \text{ cm}^{-2}$  ( $n_{3d} \sim 2.7 \times 10^{18} \text{ cm}^{-3}$ ). The average hole density is around  $7 \times 10^{12} \text{ cm}^{-2}$ , which is much higher than electron density due to the heavier effective mass and smaller diffusion length so that more holes stay inside the QW after electron-hole pairs are generated. As shown in Fig. 8(a), the emission intensity near the edge is the strongest. For  $r < 45 \text{ nm}$ , the emission strength does not change much, and this can be explained by the insignificant strain variation from the center, as shown in Fig. 5. Moreover, Fig. 8(b) shows the calculated emission peak shift and emission rates as a function of the radius of the cylindrical nanorod under an injected electron density of  $8 \times 10^{11} \text{ cm}^{-2}$ .

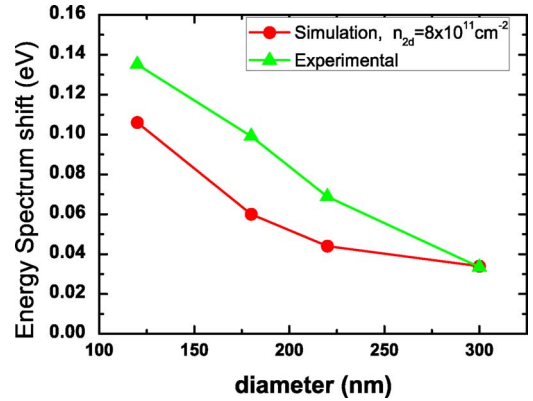


Fig. 9. Measured and calculated emission peak shift versus the nanorod diameters.

The maximum emission peak shift occurs at  $r = 58 \text{ nm}$  where 200 meV blue shift is achieved, compared to the emission from center of the nanorod. At  $r = 60 \text{ nm}$ , the strain relaxation is not the maximum at the surface so that the energy shift maximum does not occur here. The emission rate reaches the maximum at edge and decreases rapidly from  $r = 60 \text{ nm}$  to  $r = 45 \text{ nm}$ . The emission rates are almost constants for  $r < 45 \text{ nm}$ , where the electron-hole wavefunction overlap does not change too much here. Since the center of MQWs are still suffered from the strain with its magnitude comparable to that of the as-grown planar structure, the PL from the center of the nanorod contributes to the red-edge emission, which is partially overlapped with the PL from the strained region. Therefore, we believe that the majority of the nanorod PL blue shift originates from the strain-relaxed region, within a distance of  $\sim 15 \text{ nm}$  near the edge of the nanorod, as shown in Fig.8 (b). Moreover, the variation of strain tensors in the relaxation region results in a spatially varied polarization field, leading to a broadened emission spectrum.

The overall emission spectrum (in (electron volts-seconds) inverse) of the nanorod LEDs can be calculated by summing the emission spectra from different regions, which equivalently can be obtained by

$$R_{sp,total}(\hbar\omega) = \int_0^{d/2} R_{sp}(\hbar\omega, r) 2\pi r dr \quad (6)$$

where  $d$  is the diameter of the nanorod and  $r$  is the distance to the center of the nanorod. The  $R_{sp}(\hbar\omega, r)$  is already obtained, as shown in Fig. 8(b). Fig. 9 shows the comparison between calculated emission peak from (6) and experimental measurement. We find the calculated size-dependent peak shift is well-agreed with the measurements. Our calculation results show that the blue shift mainly arises from the edge strain relaxation of the MQWs. Therefore, for the larger diameter nanorods, the volume ratio of the strain-relaxed region to the strained region becomes smaller so that the blue shift also becomes smaller.

As mentioned earlier, the PL intensity of the nanorod with the smallest diameters is the strongest at low temperature. However, at room temperature, the PL intensity maximum occurs for nanorod LEDs with an average diameter of 220 nm. The effects of extraction and absorption may be neglected since they

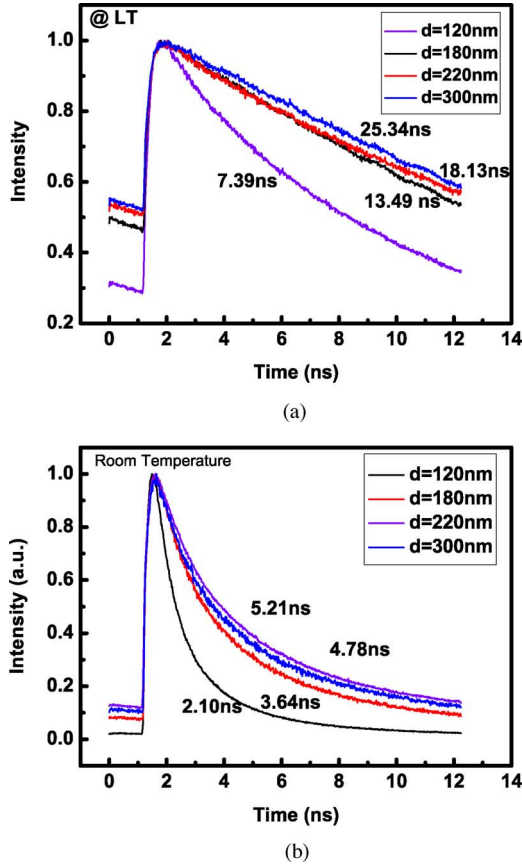


Fig. 10. (a) TRPL for nanorod LEDs with different sizes at 20 K. (b) TRPL for nanorod LEDs with different sizes at room temperature.

were measured from the same samples only at different temperatures. It is possible that the defect density contributes to the decrease of the PL intensity. Therefore, we conduct the TRPL for both cases. Fig. 10(a) and (b) shows the measured TRPL at low temperature 20 K and room temperature, respectively. As shown in Fig. 10(a), the fitted decay times are 25.34, 18.13, 13.49, and 7.39 ns for nanorod diameters of 300, 220, 180, and 120 nm, respectively. The nanorod LEDs with the diameter of 120 nm have the smallest decay time. If the carrier decaying process is dominated by radiative recombination, the smallest diameter nanorod has the best efficiency. This can be also observed with the PL spectrum intensity, as shown in Fig. 3(a). However, at room temperature, we can find that the nanorod LEDs with the diameter of 220 nm have the strongest emission intensity. However, as shown in Fig. 10(b), the TRPL shows that the decay time of 120 nm nanorod has the smallest decay time. It is well-known that the PL decay lifetime is determined by both the radiative and nonradiative processes. If the radiative lifetime dominates, the emission intensity should be strongest for the smallest nanorod size due to the smallest decay time. However, the intensity of nanorod LEDs with a diameter of 120 nm exhibits an opposing behavior, as shown in Fig. 3(b). Hence, we conclude that the nonradiative decay process dominates and reduces the emission intensities at room temperature. The nanorod LEDs with a diameter size smaller than 180 nm

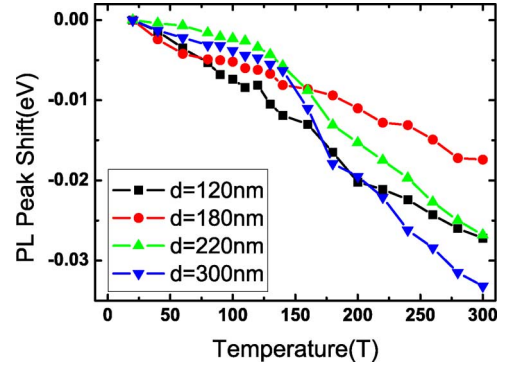


Fig. 11. Measured peak shifts as a function of temperature for nanorod LEDs with different sizes.

may have a large defect density. Although the nanorod LEDs with a small averaged diameter can increase the radiative recombination rate, the increased nonradiative recombination rate cancels the effect of radiative rate enhancement and limits the internal quantum efficiency.

Fig. 11 shows the energy peak shift versus temperature for nanorod LEDs with different diameters. In the temperature-dependent measurement, the bandgap shrinks as the temperature increases, giving rise to the red shift of the emission wavelength. Moreover, the free carriers also move rapidly, and hence are more likely to fall into localized states and then recombine. If the density of localized defect states is small, the defect states can be easily filled up. Therefore, the carriers can stay at band states, resulting in the reduction of red shift or even a small blue shift. As the temperature continues to increase, the red shift due to the bandgap shrinkage becomes dominant again and results in an s-curve for the emission peak shift. However, if the localized defect density is high, the localized states are less likely to be filled. The s-type emission peak shift therefore cannot be clearly observed. As shown in Fig. 11, the s-type peak shift is relatively obvious for nanorod LEDs with diameters of 300 and 220 nm. On the other hand, the s-curve is not as clear for those of 180 and 120 nm, indicating a considerable density of surface states. The temperature-dependent characteristics support our previous conclusion, suggesting the importance of surface passivation for nanorod LEDs with a small diameter.

## V. CONCLUSION

In conclusion, we have demonstrated the size-dependent emission characteristics of InGaN/GaN MQW nanorod LEDs using both frequency-resolved PL and TRPL measurement at different temperatures. The strain distribution and the band profile of MQWs embedded in the nanorod structures are analyzed by the VFF model and the self-consistent solver. Our calculation shows that the energy shift and spectrum broadening could be strongly related to the strain relaxation at nanorod edge ( $\sim 20$  nm from the edge). The low-temperature PL measurements and calculations show that the nanorod LEDs with the smallest averaged diameter of 120 nm have the highest radiative recombination rate due to strain relaxation. However, as

the nanorod diameter becomes smaller than 200 nm, the nonradiative recombination at surface defects starts to affect the device performance at room temperature. As a result, the internal quantum efficiency is reduced. Therefore, surface passivation is critical for boosting efficiencies of strain-relaxed InGaN/GaN nanorod LEDs.

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